



SWTEST
2026 CONFERENCE

35th
ANNIVERSARY

Micro Bump Probing: High Volume Experience Driven Capability Demonstration and Direction for Advanced 3D/2.5D Packaging



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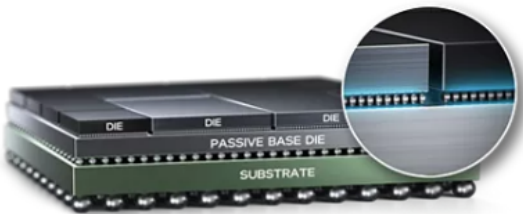
1 - Intel Foundry
2 - FormFactor

Outline

- Motivation, Background and Challenges w/ μ Bump probing
- Foveros DOW36 vs. EMIB: Layout and Probing Solutions
- Intel μ -Bump Experience: Qual Strategy, Results and HVM Production Expertise
- Summary and Outlook

Motivation

- Recent trends drive increasing demand for proven / capable micro-bump probing technologies
 - Explosive growth of AI workloads; Advanced heterogeneous integration across multiple silicon technology nodes; Aggressive interconnect pitch scaling; Known-good die (KGD)
- Intel has extensive experience with micro-bump probing in High Volume Production through the Foveros product line (HVM starting in 2019) – with plans to enable micro-bump probing on EMIB devices this year



Foveros-S 2.5D

Next generation package optimized for cost/performance.

- Silicon interposer with 4x reticle.
- Applicable in client applications.
- Ideal for solutions with multiple top die chiplets.
- Production proven: In mass production since 2019 with active base die.



EMIB 2.5D

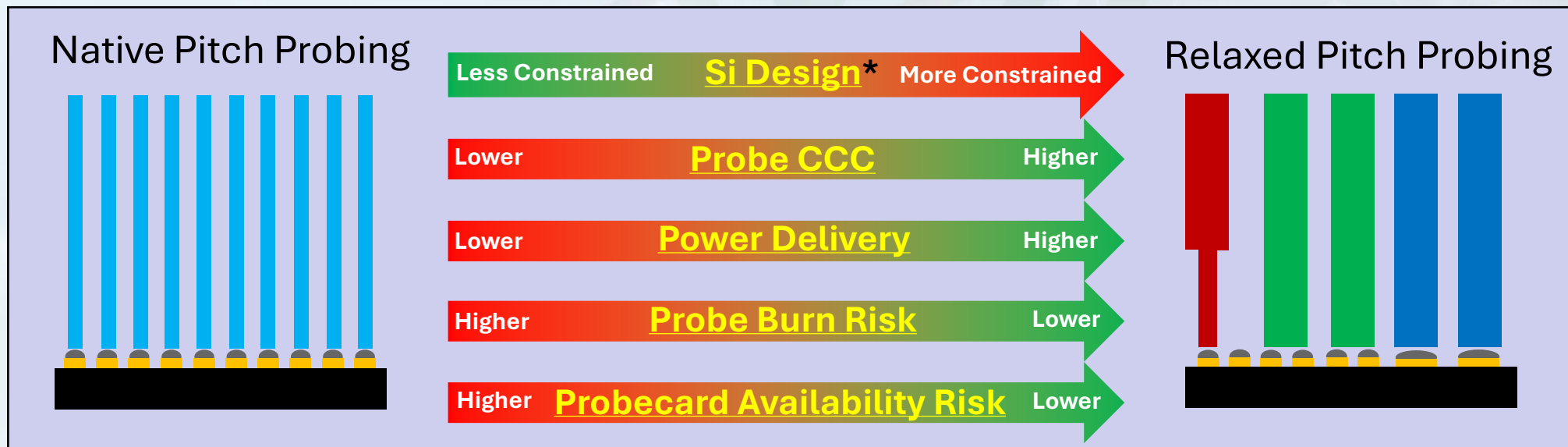
Embedded Multi-die Interconnect Bridge 2.5D.

- Efficient, cost-effective way to connect multiple complex die.
- 2.5D packaging for logic-logic and logic-high bandwidth memory (HBM).
- EMIB-M features MIM capacitors in the bridge. EMIB-T adds TSVs to the bridge.
- Silicon bridge embedded in package substrate for shoreline-to-shoreline connection.
- EMIB-T can ease the enablement of IP integration from other packaging designs.
- Simplified supply chain and assembly process.
- Production proven: In mass production since 2017 with Intel and external silicon.

General Strategies to Consider

➤ Goal to strike balance between

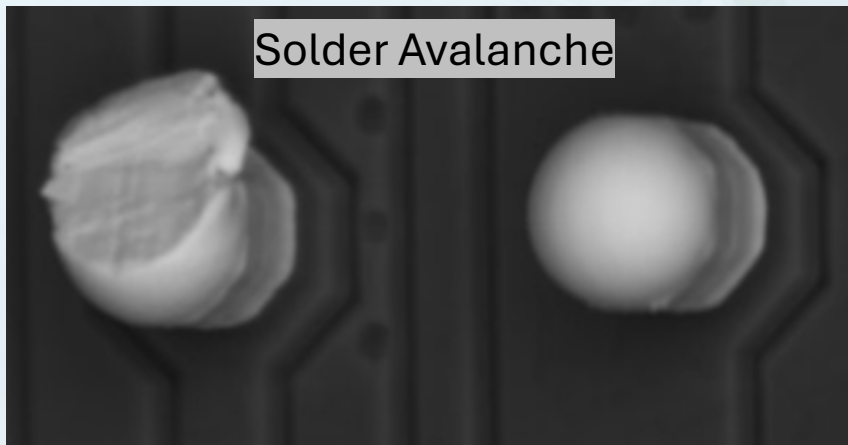
- Minimizing design constraints to enable sort/test → **Native pitch probing**
- Maximizing power delivery at sort, to improve screening efficiency and minimize risks for burns/repairs that lead to probecard availability losses and increase total cost of ownership → **Relaxed pitch probing**



* Upfront planning for bump layout design rules

Challenges with μ Bump Probing

- Manage tight radial alignment control across a fleet in mass production
- Stable and uniform electrical contact
- Uniform μ Bump deformation
- Sort/Probe induced defect modes and yield losses
- Downstream risks at assembly and reliability requiring integrated qual strategies



- **Significant and synergized efforts across Intel Foundry and FormFactor, to co-optimize probe architecture and probing process, to enable high-volume manufacturing**

Foveros-S DOW36 vs EMIB Technology

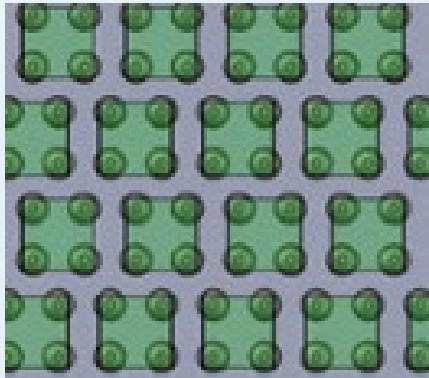
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Foveros-S 2.5D

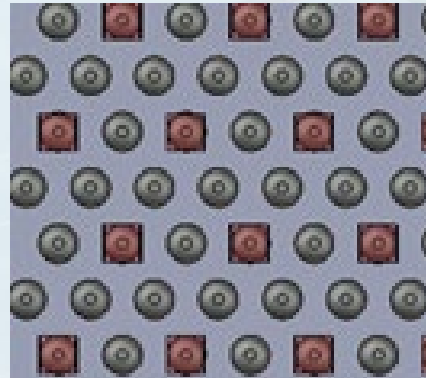


- Foveros DOW36
- Full field μ -bumps
- 18 μ m CD
- 36 μ m min bump pitch

Quad clusters (70 μ m min probe pitch)



Singles (skip-bump, 90 μ m min probe pitch by rule)



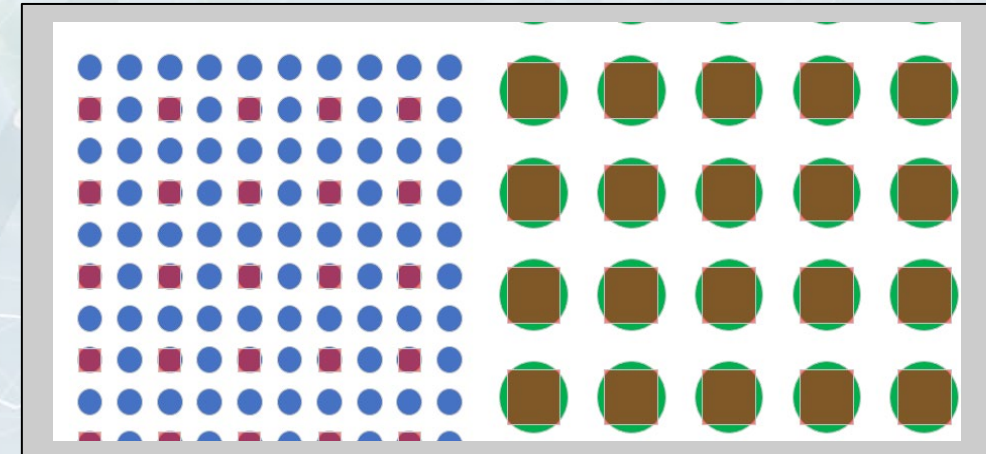
Quad Probing (Intel) – US Patent No. 12,163,982

EMIB-T 2.5D

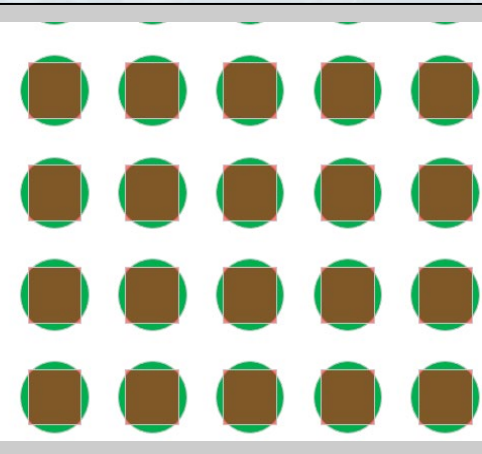


- EMIB45 μ m
- Core bumps: 65-70 μ m CD; 100 μ m min pitch
- Bridge μ -bumps: 23-28 μ m CD; 45 μ m min pitch

μ -bump (skip-bump, 90 μ m min probe pitch)



Core bump (100 μ m min probe pitch)



Both architectures require hybrid probe solutions with tight radial alignment control

μ-Bump Probing Solutions

Probe	Min Square Pitch	Tip Size	CCC*	Probe Force	Alignment	Hybrid Option
Single-IO-70	72x62μm	28x28μm	0.6A	0.8gf	≤7 μm (build) ≤10 μm (accept)	Yes
QUAD-70-A	72x67μm	47x47μm	0.7A	1.3gf		
QUAD-70-B				2.7gf		
Bridge-IO	78x78μm	28x28μm	1.1A	1.3gf	≤10 μm (accept)	Yes
Core-90	78x78μm	50x56μm	1.3A	2.2gf		
Core-110	78x95μm	50x60μm	1.4A	2.5gf		
Core-140	75x125μm	50x60μm	1.7A	2.7gf		

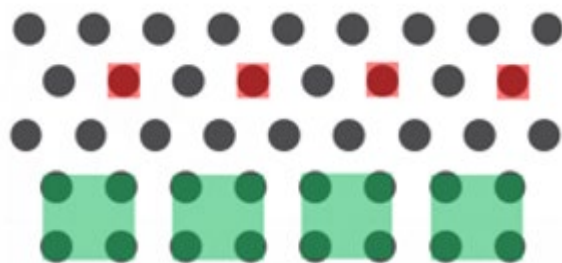


In Qual

Intel Foundry Data

*MeGP is available and increases effective CCC

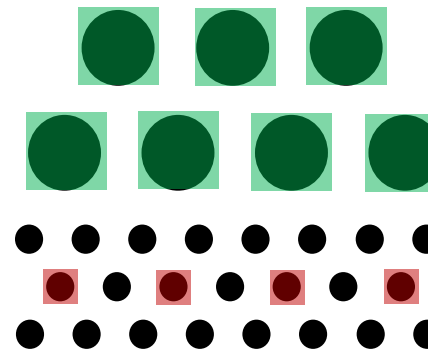
Multi-Bump



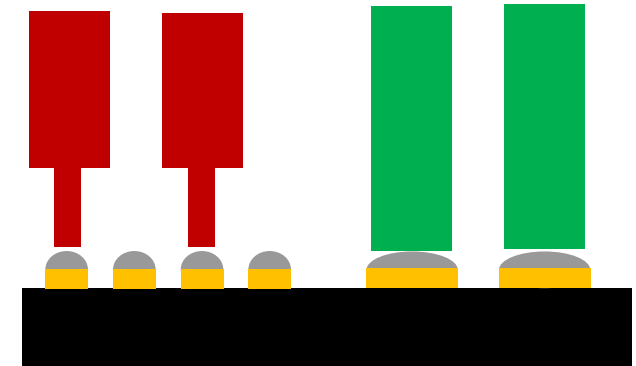
Ex: Foveros DoW36



Mix CD Bump



Ex: EMIB45 Mixed CD

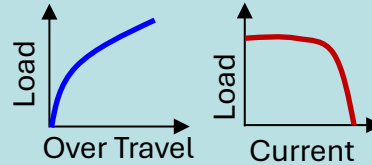


Typical Qualification Plan

Select/develop probe(s) to meet critical sort requirements



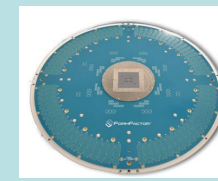
Intel + FFI test coupon characterization → probe finalized



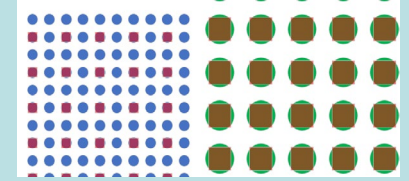
Materials Characterization (SEM, EDS, X-ray)

Build test vehicles (TV) to validate required envelope

TV: Probe card



TV: Si



Assess probing performance at COLD/HOT/MERGED socket
(start at COLD; then switch to HOT for die sort only)

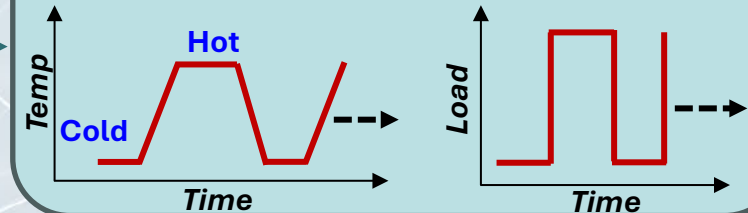
Probe performance validation using baseline recipe for CRES and shorts

Probing Process optimization for high volume readiness

- Clean parameters
- Over-Travel
- Card-to-card variation
- Module to module variation

Iteration, recipe optimization and recipe hardening

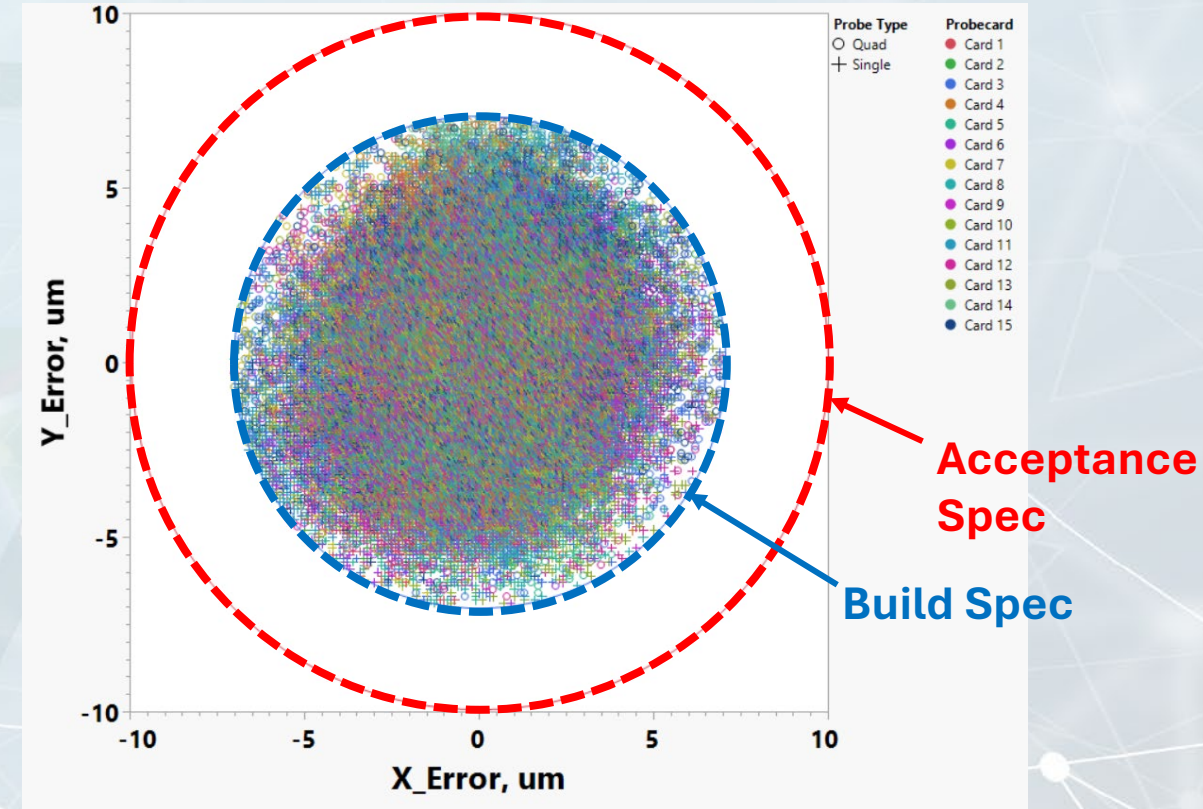
Thermomechanical cycling, fatigue test and lifetime



Bump deformation assessments to validate no downstream risks

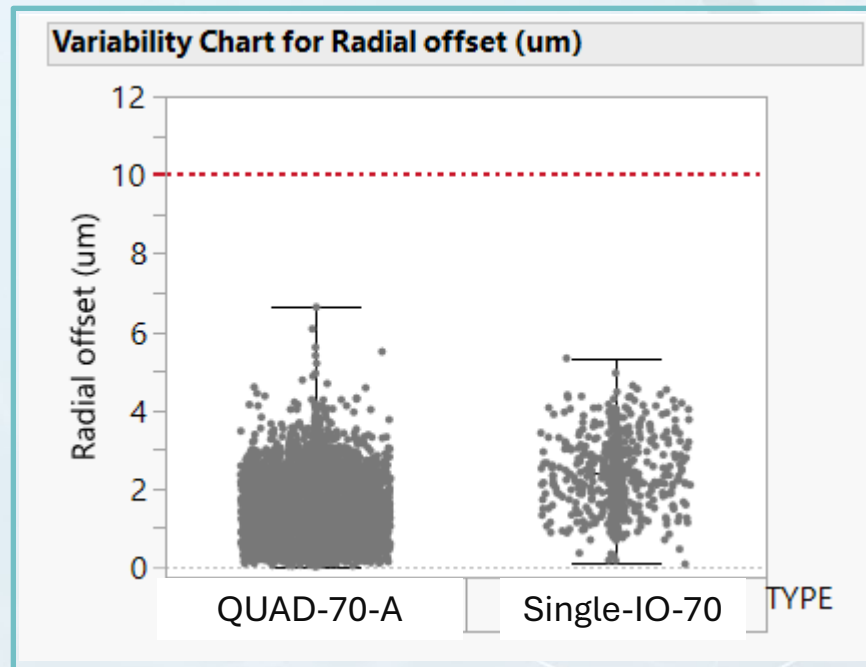
Hybrid Probing Radial Alignment (FFI Outgoing)

- Foveros DOW36 HVM example
- FormFactor outgoing radial alignment from a representative product (Product A)
- 243K springs across 15 cards, including QUAD and Single probe types

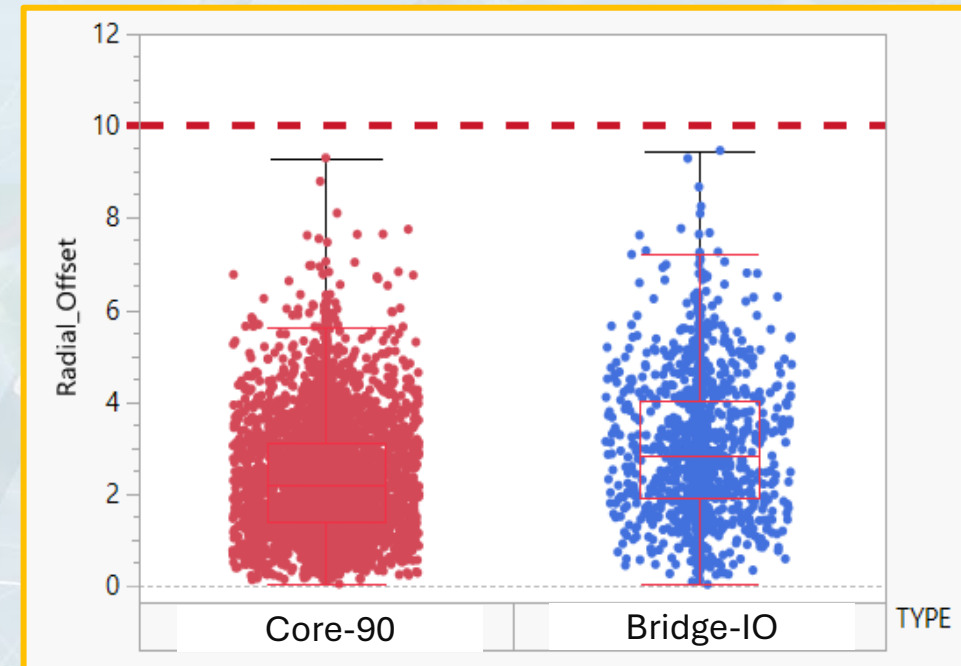


Hybrid Probing Radial Alignment (Intel Foundry Incoming)

Foveros DoW36 – Product B
QUAD-70-A + Single-IO-70 probe alignment
(2 heads, 10k probes)



EMIB45um Mixed Pitch – TV1
Core-90 + Bridge-IO probe alignment
(3 heads, 19k probes, *in development*)



Good radial alignment control demonstrated on many Foveros products in high volume

Foveros DOW36 Mass Production Summary vs EMIB Mixed Pitch Probing

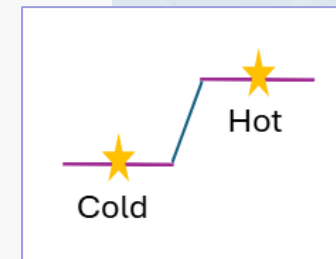
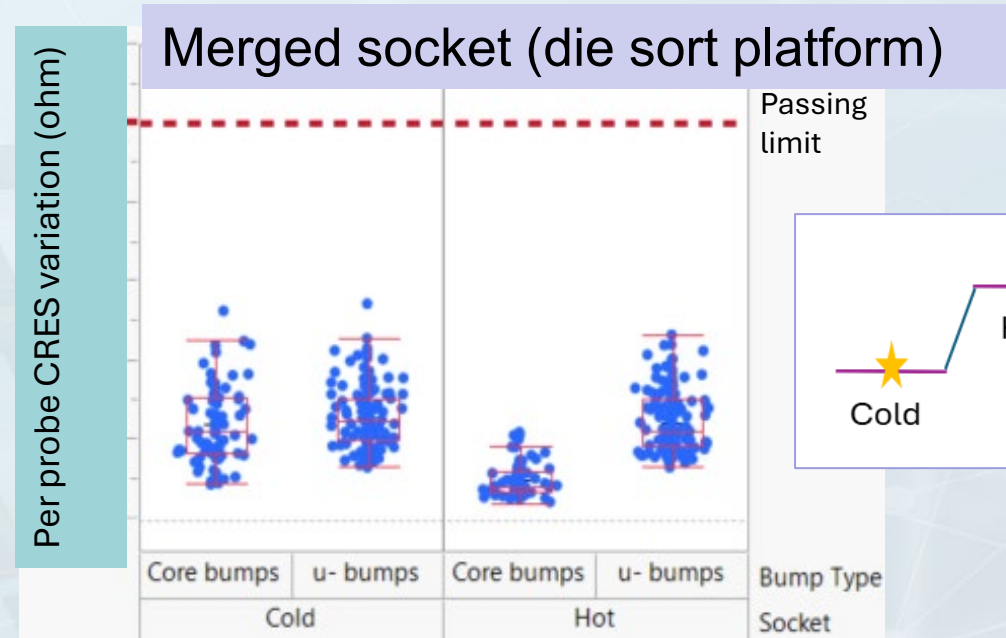
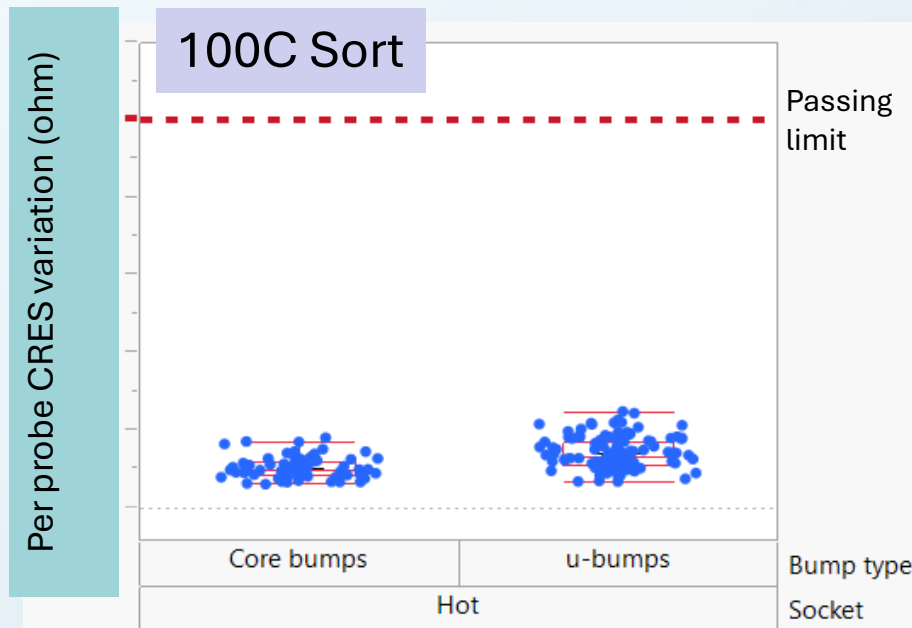
2019 – 2026+

2026 →

Metric	Foveros DOW36	EMIB45 Mixed Pitch Probing
Bump info	Full field μ -bumps 18 μ m CD 36 μ m min pitch	Mixed CD Core bumps: 65-70 μ m CD; 100 μ m min pitch Bridge μ -bumps: 23-28 μ m CD; 45 μ m min pitch
Probing pitch	Quad clusters (70 μ m min pitch) Single μ Bump (90 μ m min pitch by rule)	Core bumps (100 μ m min pitch) μ -bumps (90 μ m min pitch)
Radial Alignment Target	$\leq 10 \mu\text{m}$	$\leq 10 \mu\text{m}$
Technology Readiness	In Mass Production since 2019 Wafer- and Die-Sort	<i>Under development</i> Technology Certification by Q3'26
High Volume Production Experience	Products: 25+ (multiple sites) Wafers: 300K+ FFI Probe Heads: 1500+	--
Probe Card Availability	~ 90% (Average across products)	--
Probe card Mean Time to Failure (Card returns per 100 wafers)	1 – 2 for standard probe maintenance (Average across products)	--

Performance on EMIB45 Test Vehicle

- Representative CRES results from EMIB45 Mixed CD TV using hybrid (Core-90+ Bridge-IO) probe card



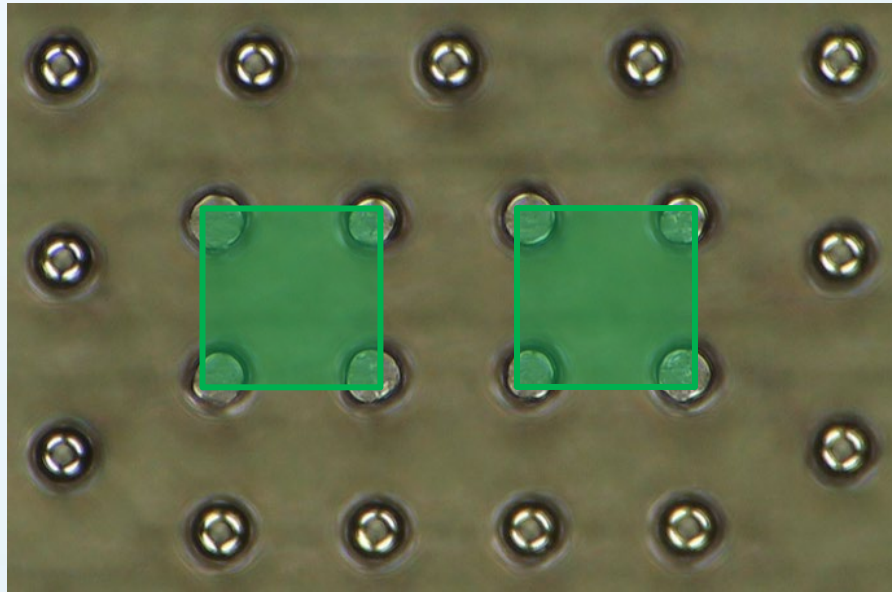
COLD → -10C
HOT → 100C

- Methodology:
 - Run wafer(s) multiple times and assess the per-pin CRES stability vs. different process variables (temperature, overtravel, cleaning parameters, etc)
 - Validate no issues with process or probe card induced leakage
 - Freeze the most optimal recipe for mass production

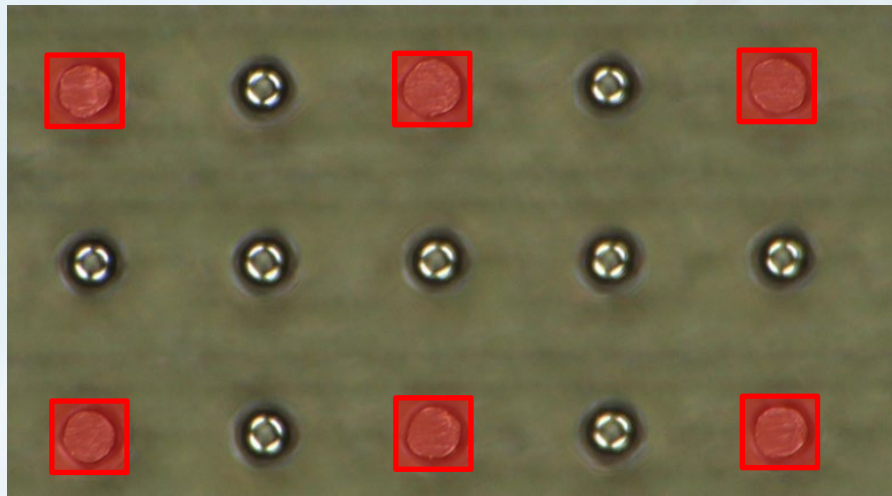
Intel sort performance using FormFactor probes have healthy electrical performance at Cold/Hot & Merged socket test conditions

Bump Deformation Examples

Foveros DoW36

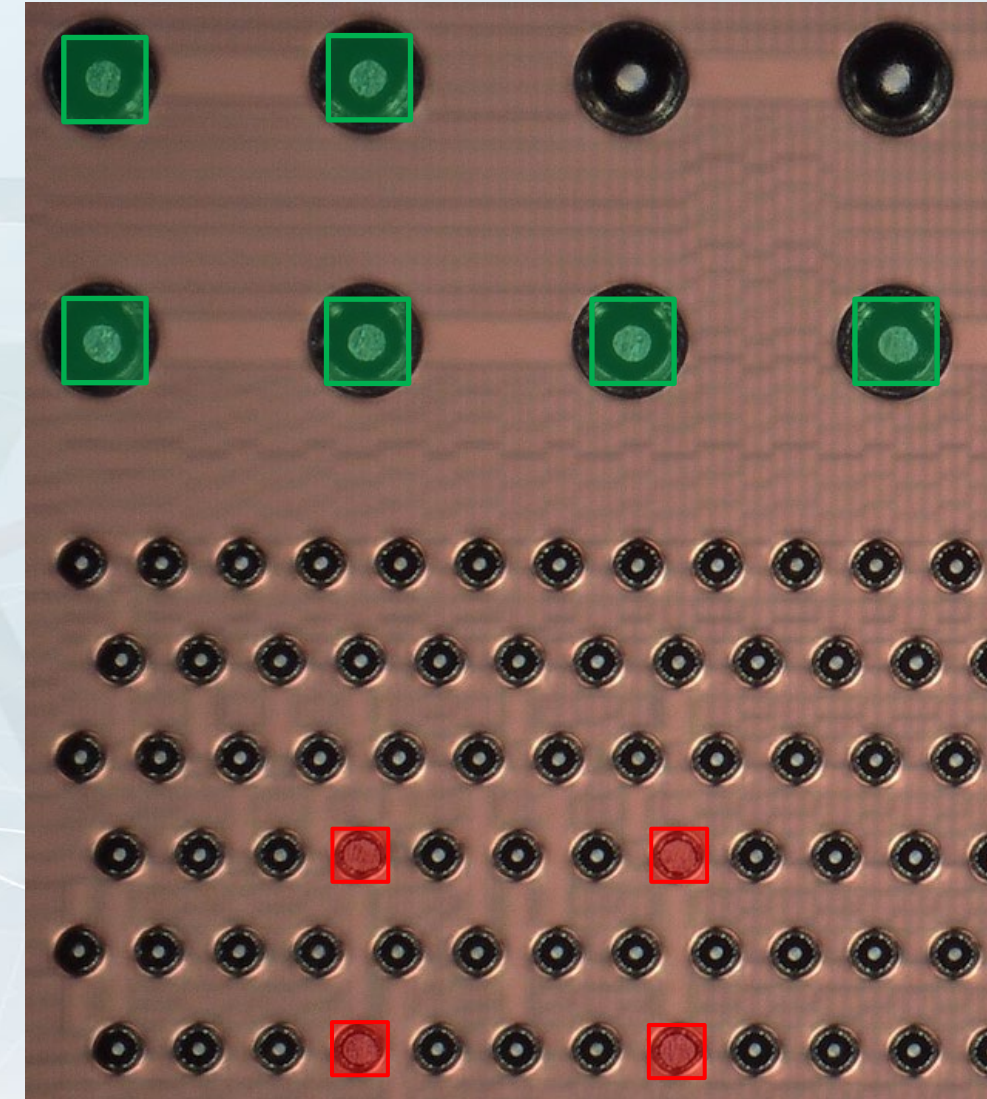


QUAD



Single

EMIB45 Mixed CD



Core

Bridge

Well-centered and symmetric bump contacts with Intel probing process on microbumps

General Considerations for Overcoming Downstream Risks

- Optimizing probe tip size and force to manage solder bump deformation
- Good radial alignment control to minimize asymmetric bump deformation
- Controlling the maximum die temperature throughout the test
- Optimizing the Test time at HOT
- Managing the number of touchdowns and/or using post sort reflow to preserve the bump coplanarity
- Assembly and reliability DOEs to quantify safe envelope

Summary and Future Outlook

- Intel Foundry has significant μ -bump probing experience that is well established in mass production across multiple sort platforms and factories
- FormFactor is a worldwide leader in probecard supply enabling high volume test on μ -bump interfaces
- The teams are leveraging proven expertise and Foveros DOW36 HVM experience to develop μ -bump capable sort solutions for EMIB-T advanced packaging
- Collaboration as demonstrated here keeps probe technology and packaging developments aligned, helping identify and address probing challenges before they impact yield

Acknowledgements and Questions



- Thank you to Intel Foundry and FormFactor colleagues for all of your contributions
- Questions?